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# Outline

- 1. Introduction
- 2. Differences in On-Chip Inductance Consideration
- 3. Significant Frequency of High-Speed Pulse
- 4. Inductance Calculations
- 5. Proximity and Skin Effects
- 6. Circuit Modeling and Inductance Impacts
- 7. Self-Inductance Screening Rules
- 8. Mutual-Inductance Screening Rules
- 9. Efficient Inductance Modelings
- 10. Inductance Test Chip Benchmark
- 11. Techniques to Minimize Inductance Effects





#### Introduction

On-Chip Inductance effects have become increasingly significant because:

1) For performance considerations, some global signal and clock wires are routed with large widths and thicknesses at the top levels of the metal to minimize delays. This decreases the resistance of the wires, making their inductive impedance comparable to the resistive part.

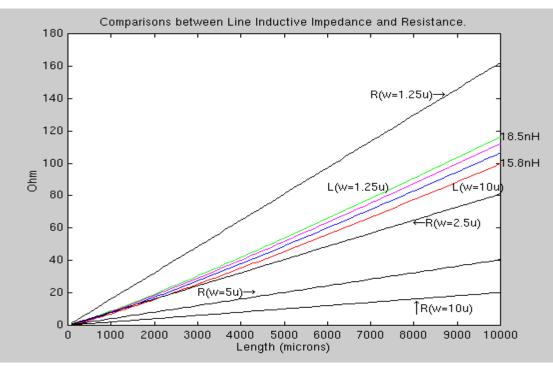
There is more to impedance than resistance:  $Z = R + j\omega L$ . When  $\omega L$  is comparable to R, inductive effects must be considered.





#### Partial-Self-Inductance Increases Super-linearly:

$$L(nH) = 2l \times \left[ \ln \left( \frac{2l}{w+t} \right) + 0.5 - k \right]$$



Resistance and inductive reactance of *Al* wires at 1GHz for different lengths and widths.



#### Introduction (cont.)

On-Chip Inductance effects have become increasingly significant because:

 As the clock frequency increases and the rise times decrease, electrical signals comprise more and more high-frequency components, making the inductance effects more significant.

| Year | Frequency (GHz) |
|------|-----------------|
| 1999 | 1.25            |
| 2002 | 2.1             |
| 2005 | 3.5             |
| 2008 | 6.0             |
| 2011 | 10.0            |
| 2014 | 13.5            |

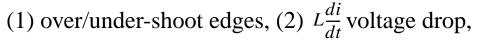
Table 1: SIA Roadmap (1999 Rev.)

1.71x every 3 years

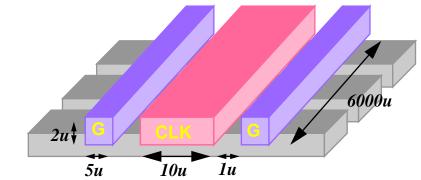


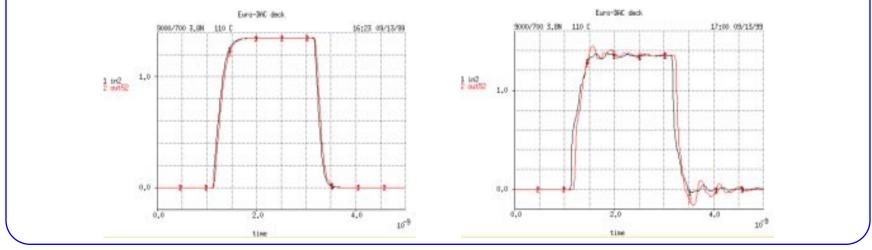


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(3) long range crosstalk, and (4) f-dependent R







## Introduction (cont.)

On-Chip Inductance effects have become increasingly significant because:

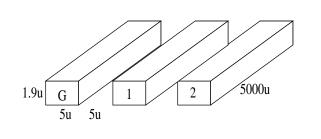
- 3) With the increase of chip size, it is fairly typical that many wire are long and run in parallel, which increases the inductive crosstalk and delay.
- 4) With the push of performance, some low-resistivity metals,
  e.g. *Cu* wires, have been explored to replace *Al* in order to minimize wire **RC** delays. This could make the wire inductive reactance larger than the resistance.



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# **Differences in On-Chip Inductance Consideration**

1. The internal inductance of on-chip wires needs to be considered because the skin depths at the frequencies that we consider are comparable to the wire thickness or width. Most electrical currents flow inside the wires.



Inductance is calculated by

$$\tilde{L} = \frac{1}{c^2} \tilde{C}^{-1}$$

in RC2.

| Frequency  | RI3  | RC2  | % difference |
|------------|--|--|--------------|
| 1 GHz      | $\begin{bmatrix} 3.768 \times 10^{-9} & 2.563 \times 10^{-9} \\ 2.563 \times 10^{-9} & 5.125 \times 10^{-9} \end{bmatrix}$ | $\begin{bmatrix} 2.983 \times 10^{-9} & 2.133 \times 10^{-9} \\ 2.133 \times 10^{-9} & 4.266 \times 10^{-9} \end{bmatrix}$ | 23%          |
| 100 GHz    | $\begin{bmatrix} 3.538 \times 10^{-9} & 2.425 \times 10^{-9} \\ 2.425 \times 10^{-9} & 4.850 \times 10^{-9} \end{bmatrix}$ |  | 15%          |
| 10,000 GHz |  | $\begin{bmatrix} 2.983 \times 10^{-9} & 2.133 \times 10^{-9} \\ 2.133 \times 10^{-9} & 4.266 \times 10^{-9} \end{bmatrix}$ | 10%          |

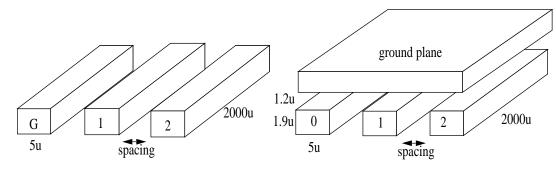


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# **Differences in On-Chip Inductance Consideration**

2. Due to the lack of highly conductive ground plane on chip, the mutual couplings between wires cover very long ranges and decrease very slowly with the increase of spacing.



(a)

(b)

| Spacing | $K_{12}$ of (a) | compared with<br>1um-spacing | <i>K</i> <sub>12</sub> of (b) | compared with<br>1um-spacing |
|---------|-----------------|------------------------------|-------------------------------|------------------------------|
| 1u      | 0.73            | 100%                         | 0.29                          | 100%                         |
| 10u     | 0.57            | 78%                          | 0.034                         | 11%                          |
| 50u     | 0.54            | 74%                          | 0.0059                        | 2.0%                         |
| 100u    | 0.53            | 72%                          | 0.0038                        | 1.3%                         |

#### Why the silicon substrate cannot be considered as a ground plane?

- 1. The resistivity of the lightly doped substrate layer is about two million times larger than aluminum.
- 2. The substrate is too far away from the high-speed buses or clock wires.



# **Differences in On-Chip Inductance Consideration**

3. The inductance of on-chip wires is not scalable with length. (Their self-inductance increases with length at *n log n* rate.) Unfortunately, no good approximation formula exists for mutual inductances of two parallel lines of unequal lengths or unequal dimensions.

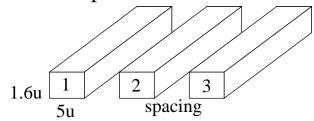
Mutual inductance for two parallel, same-dimension lines of length l and spacing D is

$$\frac{{}^{\mathrm{L}}o^{l}}{2\pi} \left[ \ln\left(\frac{2l}{D}\right) - 1 + \frac{D}{l} \right]$$



#### What makes it more difficult to consider inductance than capacitance?

1. Inductance has long range effects. Hence, it is difficult to determine the current return paths.



| Spacing | L13 /u     | C13 /u    |
|---------|------------|-----------|
| 2u      | 7.94 e-13  | 7.61 e-17 |
| 50u     | 7.806 e-13 | 0.98 e-17 |
| 100u    | 4.84 e-13  | 0.76 e-17 |

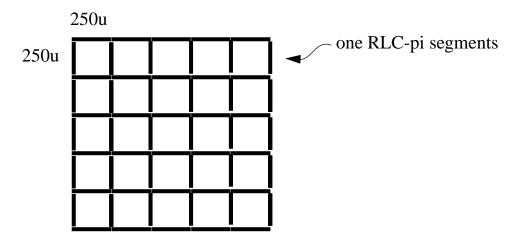
 Table 1: Comparisons of L13 and C13

- 2. Inductance is not scalable.
- 3. Inductance results in many high frequency poles and zeros, making Reduced Order Model Approximation difficult.





#### **Power Grid Example**



The *L* matrix after neglecting orthogonal coupling will still be of the dimension 6400, or 80\*80, for a typical chip!

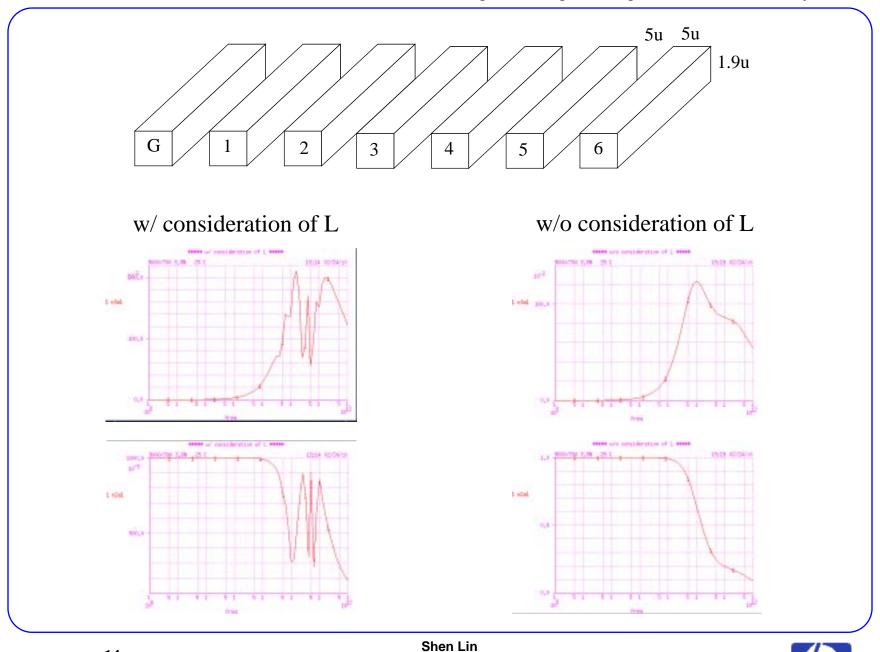
Simply discarding small mutual inductance terms can render L indefinite and result in an unstable circuit model.

|   | 13.7                                      | 8.595 | 5.375 | 5.34  |     |
|---|---|-------|-------|-------|-----|
|   | 8.595                                     | 13.7  | 5.34  | 5.375 | VS. |
|   | 5.375                                     | 5.34  | 13.7  | 8.595 |     |
|   | 5.34                                      | 5.375 | 8.595 | 13.7  |     |
| e | eigen-values = [5.07, 5.14, 11.58, 33.01] |       |       |       |     |

|   | 13.7  | 8.595 | 5.375 | 0     |
|---|-------|-------|-------|-------|
| • | 8.595 | 13.7  | 0     | 5.375 |
|   | 5.375 | 0     | 13.7  | 8.595 |
|   | 0     | 5.375 | 8.595 | 13.7  |

eigen-values = [16.92, 10.48, 27.67, -0.27]

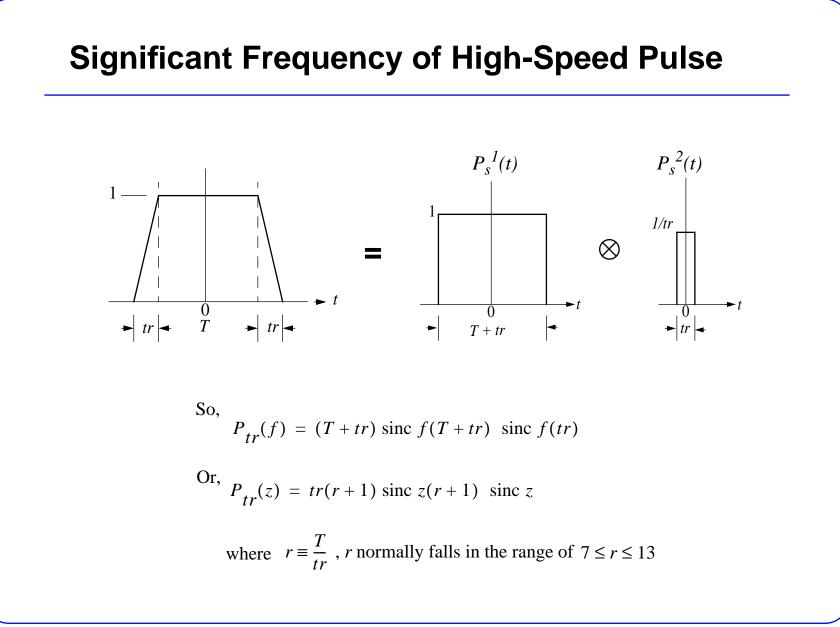




ASIC/SOC 2000 Interconnect Modeling and Design for Giga-Hertz Circuits and Systems

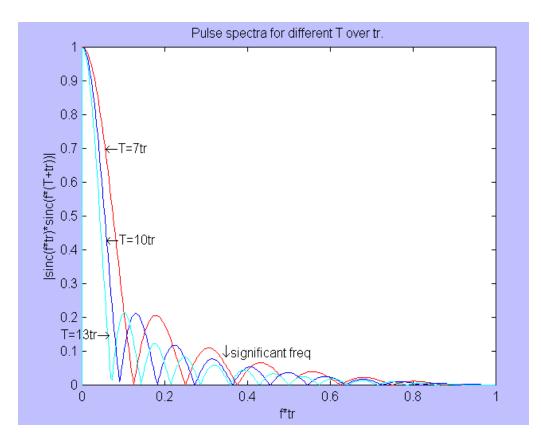


Hewlett Packard shenlin@hpl.hp.com





#### Pulse spectra for different T over tr





# **Significant Frequency of High-Speed Pulse**



$$S(r) = \frac{0}{\sum_{k=0}^{\infty} |\operatorname{sinc} z(r+1) \operatorname{sinc} z| dz}{\int_{\infty}^{\infty} |\operatorname{sinc} z(r+1) \operatorname{sinc} z| dz}$$

S(r) is a monotonic function.

S(7) = 0.85, S(10) = 0.858, S(13) = 0.862.



# **Significant Frequency of High-Speed Pulse**

Significant Frequency is defined as

$$f_s = \frac{0.34}{t_r}$$

#### **Properties:**

- 1. About 15% of the frequency components lie at frequencies higher than the significant frequency.
- 2. The magnitude of the pulse's spectrum at at frequency higher than the significant frequency is less than 10% of its maximum value. Beyond the significant frequency, the spectral amplitude rolls off much faster than 20 *dB/decade*.



#### **Inductance Calculation**

Maxwell's equations:

$$\nabla \times \boldsymbol{E} = -\frac{\partial \boldsymbol{B}}{\partial t}$$
$$\nabla \times \boldsymbol{H} = \frac{\partial \boldsymbol{D}}{\partial t} + \boldsymbol{J}$$
$$\nabla \bullet \boldsymbol{B} = 0$$
$$\nabla \bullet \boldsymbol{D} = \boldsymbol{\rho}$$

Maxwell's equations in the sinusoidal steady state:

 $\nabla \times \boldsymbol{E} = -j\omega\mu\boldsymbol{B}$  $\nabla \times \boldsymbol{H} = j\omega\varepsilon\boldsymbol{D} + \boldsymbol{J}$  $\nabla \bullet \boldsymbol{H} = 0$  $\nabla \bullet \boldsymbol{E} = \frac{\rho}{\varepsilon}$ 





Since  $\nabla \bullet H = 0$ , *H* much be the curl of another vector. Hence we introduce the vector potential *A*, such that

 $\mu H = \nabla \times A \quad \text{and} \quad \nabla \bullet A = 0.$ 

With magneto-quasi-static assumption,

$$\mu \boldsymbol{J} = \mu \nabla \times \boldsymbol{H} = \nabla \times \nabla \times \boldsymbol{A} = \nabla (\nabla \bullet \boldsymbol{A}) - \nabla^2 \boldsymbol{A}$$

Therefore,

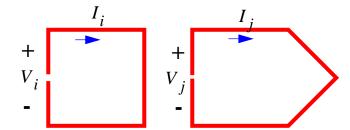
$$-\nabla^2 A = \mu J$$





Green's function solution for the Poisson's equations:

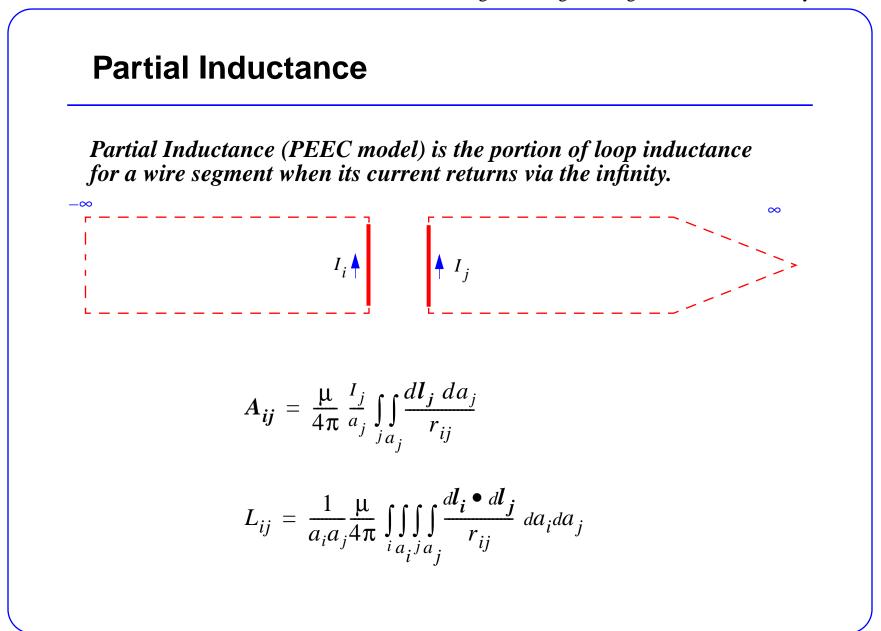
$$A(r) = \frac{\mu}{4\pi} \int_{V'} \frac{J(r')}{|r-r'|} dv'$$





$$L_{ij} = \Psi_{ij} / I_j = \frac{1}{a_i a_j} \frac{\mu}{4\pi} \oint_{i a_i j a_j} \frac{dl_i \bullet dl_j}{r_{ij}} da_i da_j$$

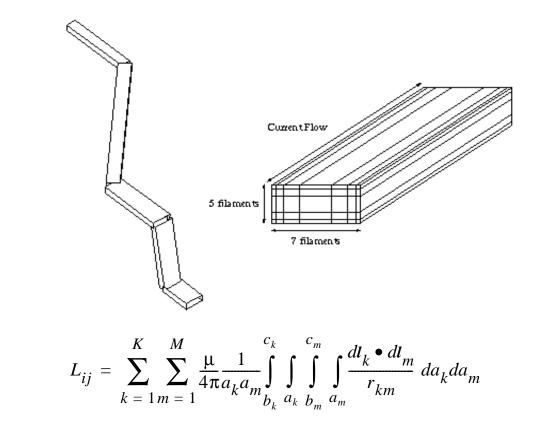




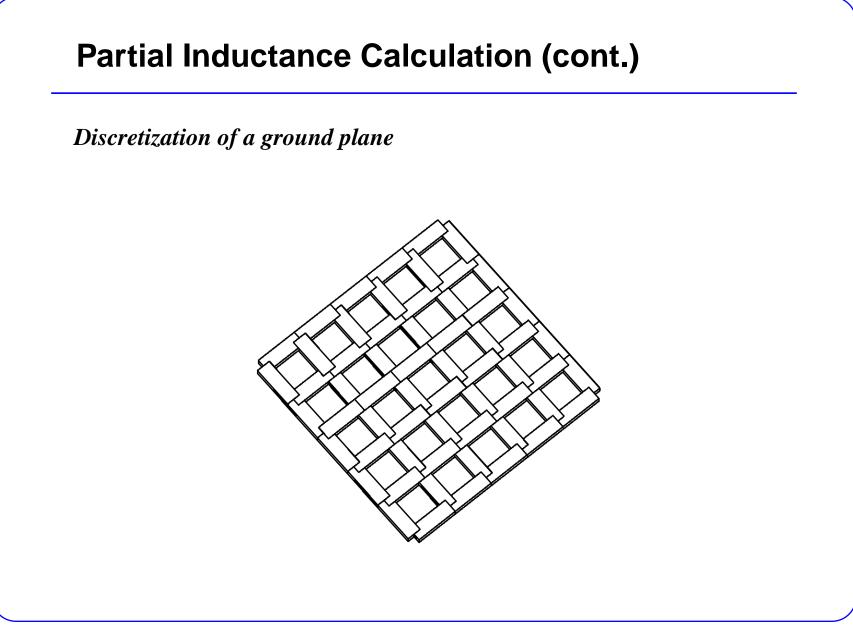


# **Partial Inductance Calculation**

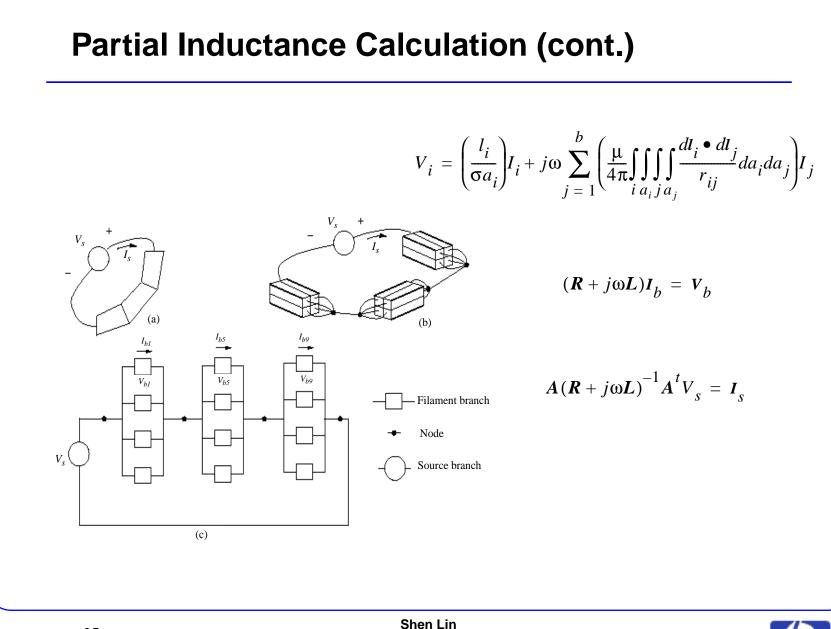
Partial Inductance calculation of an interconnect divided into multiple segments, each of which is a bundle of multiple filaments:















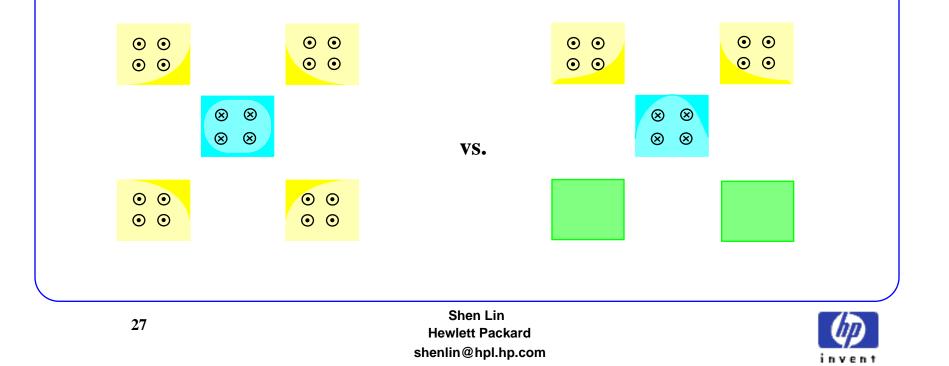
## **Properties of Partial Inductance**

- 1. Partial self- and mutual- inductances are based on geometry only.
- 2. They may be solved by using a 2D/3D field solver such as Avanti's *Raphael* or MIT's *FastHenry*.
- 3. The return path or the current loop may be determined through SPICE simulations.
- 4. The partial self- and mutual- inductances *may be* frequency- and proximity- dependent.



## **Proximity Effects**

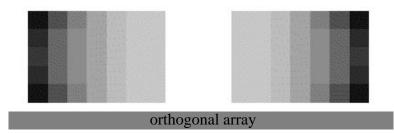
Depending on how the current flows among wires (**flow directions** and **current distributions**) at different **frequencies**, the current densities are different. This changes each wire's impedance, including resistance and inductance, at different frequencies.



# **Proximity Effects (cont.)**

|  | 35 |  |
|--|----|--|
|  |    |  |
|  |    |  |
|  |    |  |
|  |    |  |

Current density plot for odd-mode two-coupled conductors on top of an orthogonal array with width 2.5um, thickness 1.9um, spacing 1.2um, distance to orthogonal array 1.2um, and 2000um in length. The current density is higher (5%) at the near end of two-coupled conductors at 4GHz due to the current flowing in the opposite direction.



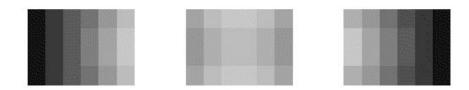
Current density plot for even-mode two-coupled conductors on top of an orthogonal array with width 2.5um, thickness 1.9um, spacing 1.2um, distance to orthogonal array 1.2um, and 2000um in length. The current density is higher (4%) at the far end of two-coupled conductors at 4GHz due to the current flowing in-phase.



## **Proximity Effects (cont.)**



Current density plot for three-coupled conductors on top of an orthogonal array with width 2.5um, thickness 1.9um, spacing 1.2um, distance to the ground plane 1.2um, and 2000um in length. The currents flow in the same phase in the three conductors. The current density of the center conductor is quite uniform due to the conflicting forces of the skin-effect pushing the current outward from the center and the proximity-effect given by the two outer conductors pushing the current inside toward the center. The maximum difference in current density is about 4% at 4GHz in this case.



Current density plot for three-coupled conductors on top of an orthogonal array with width 2.5um, thickness 1.9um, spacing 1.2um, distance to the orthogonal array 1.2um, and 2000um in length. The currents flow in the same phase in the outer two conductors but in the opposite phase in the center conductor. Interestingly, the current density can be differed by more than 7% in this case at 4GHz.



# **Proximity Effects (cont.)** Current density plot for six-coupled conductors on top of an orthogonal array with width 2.5um, thickness 1.9um, spacing 1.2um, distance to the ground plane 1.2um, and 2000um in length. The same-phase ac voltage is applied in all the conductors. The maximum difference in the current density is 8% in this case at 4GHz. Current density plot for six-coupled conductors on top of an orthogonal array with width 2.5um,

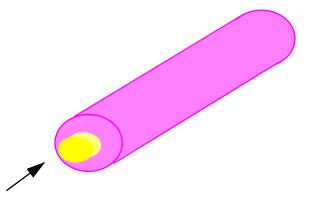
thickness 1.9um, spacing 1.2um, distance to the ground plane 1.2um, and 2000um in length. The same ac voltage is applied in the center four conductors while the outer two conductors grounded. This plot shows the current density of the conductors. The maximum difference in the current density is about 34% in these six conductors.



#### **Skin Effects**

Skin effect is the exponential increase of current concentration near the conductor surface as the frequency, the conductivity, and the permeability of the conductor are increased.

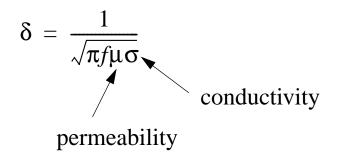
$$E_{z} = E_{0}e^{-x/\delta}e^{-jx/\delta}$$
$$J_{z} = J_{0}e^{-x/\delta}e^{-jx/\delta}$$





## **Skin Depth**

The skin depth is the depth of penetration into the conductor at which the magnitudes of the field and the current decrease to 1/e (about 36.9%).



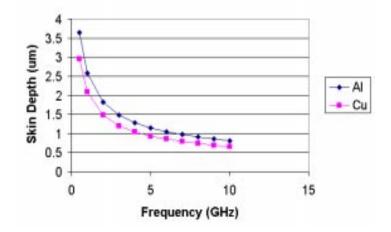


## **Skin Effects (cont.)**

Skin Depth versus Frequency for Aluminum and Copper Interconnects

| Frequency<br>(GHz) | δ for Al<br>(micrometer) | δ for Cu<br>(micrometer) |
|--------------------|--------------------------|--------------------------|
| 0.5                | 3.651                    | 2.955                    |
| 1                  | 2.581                    | 2.089                    |
| 2                  | 1.825                    | 1.478                    |
| 3                  | 1.490                    | 1.206                    |
| 4                  | 1.291                    | 1.045                    |
| 5                  | 1.154                    | 0.934                    |
| 6                  | 1.054                    | 0.853                    |
| 7                  | 0.976                    | 0.790                    |
| 8                  | 0.913                    | 0.739                    |
| 9                  | 0.860                    | 0.697                    |
| 10                 | 0.816                    | 0.661                    |

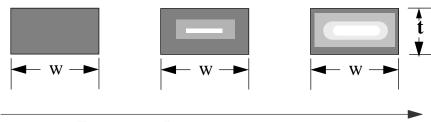
Skin Depth vs. Frequency





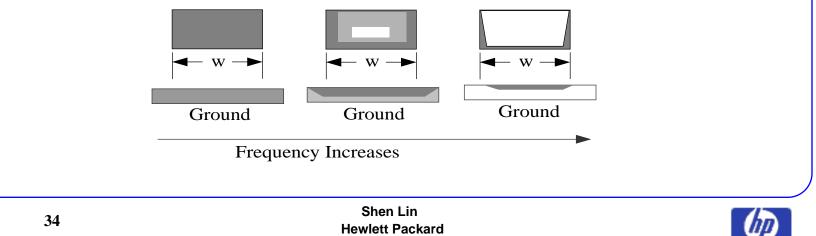
# Skin Effects (cont.)

Current distribution versus frequency in an isolated conductor:



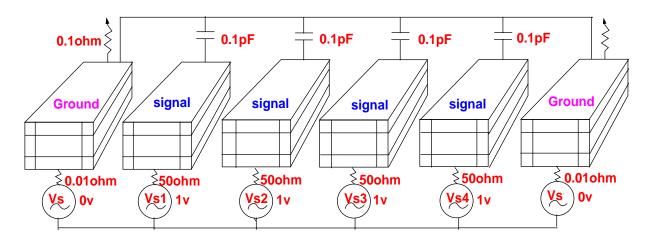
Frequency Increases

Current distribution versus frequency in a conductor over a ground plane:



# **Cope with Proximity and Skin Effects using PEEC**

By using fine filament approximations of wires. So, it is a trade-off between CPU time spent on SPICE simulations and accuracy.



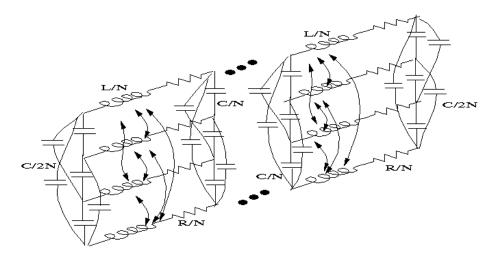
Multiple single bar composition of each rectangular conductor in Raphael RI3 is used to model the skin-effect and proximity-effect induced current density on the six conductor case, for example. Current value is monitored during SPICE simulation of the formulated RLC deck of this six conductor case. All the other examples such as two conductors or three conductors are modeled and simulated in a similar fashion. In this case, the current density is monitored at the far end of the conductors.





# **Circuit Modeling**

- 1. Run Raphael RI3 to get the inductances of the multi-conductor system at the *significant frequency*.
- 2. Run Raphael RC2/RC3 to determine the p-u-l coupling capacitances.
- 3. Partition the multi-conductor system into *N* sections and form the RLC equivalent circuit with all couplings for each segment.



The equivalent RLC circuit for the four-wire structure with Half-sections for line termination.



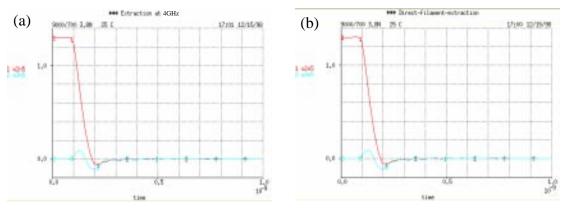


#### How many sections, N, or how short each section should be?

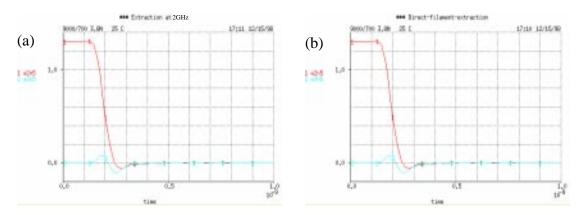
At and above the cutoff frequency  $\omega_h = \frac{2}{\sqrt{LC}}$ , the input impedance is purely imaginary, and no power of those frequencies can be delivered to the line. Therefore, we must let the cutoff frequency well above the highest frequency of interest, which determines the *L* and *C*, or the section length.



# The resistances and inductances extracted at the significant frequency achieve an accuracy of frequency-dependent resistance and inductance:



Comparisons between waveforms at the far ends of wire2 and wire3 from the (a) extraction-at-4GHz circuit; (b) direct-filament-extraction circuit.



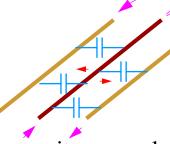
Comparisons between waveforms at the far ends of wire2 and wire3 from the (a) extraction-at-2GHz circuit; (b) direct-filament-extraction circuit.



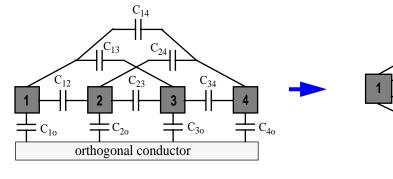
# **Circuit Modeling (cont.)**

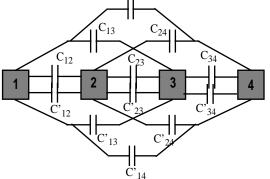
#### Common mistakes:

- 1. By assuming the inductances are scalable.
- 2. By conjecturing PEEC over-estimates the inductances since it ignores high frequency returns through coupling capacitors.

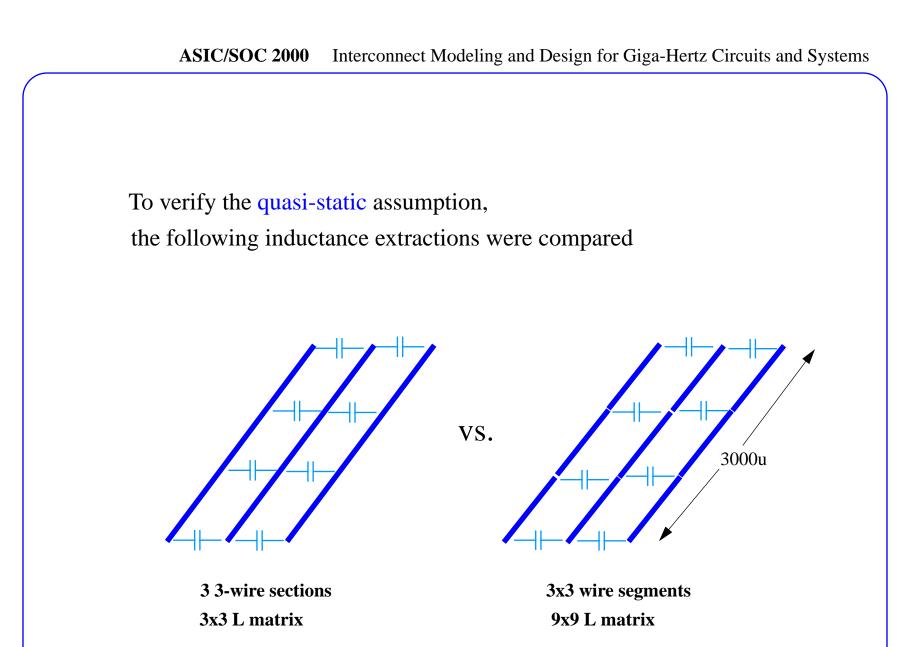


3. By assuming the capacitors coupled to other layers are grounded.

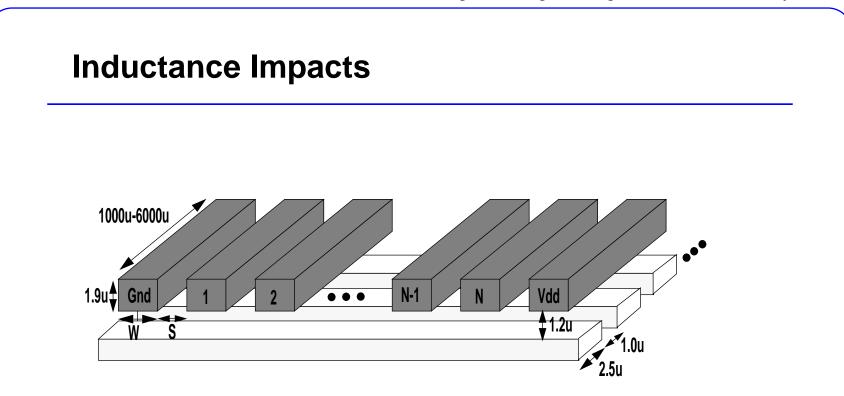












An interconnect structure with N signal wires,  $1000 \,\mu m$  to  $6000 \,\mu m$  long,  $1.9 \,\mu m$  thick, W of width, and sandwiched by Gnd and Vdd wires. The spacing between the wires is S. The gap to the orthogonal layer below is  $1.2 \,\mu m$ .



### **Inductance Impacts (cont.)**

StructureswiCross-talk comparisons<br/>between the cases with<br/>and without the<br/>consideration of inductance: $1000 \ \mu m$  -long $Z_D$ 0.8um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire $2000 \ \mu m$  -long $Z_D$ 0.8um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 8-signal-wire2.5um-wide 16-signal-wire2.5um-wide 16-signal-wire5um-wide 16-signal-wire5um-wide 16-signal-wire $4000 \ \mu m$  -long $Z_D$ 0.8um wide 8-signal-wire2.5um-wide 8-signal-wire

| Structures                            | with inductance    | w/o inductance | % error |  |  |  |
|---------------------------------------|--------------------|----------------|---------|--|--|--|
| 1000 μ <i>m</i> -long                 | $Z_{DRV} = 72$ Ohm |                |         |  |  |  |
| 0.8um-wide 8-signal-wire              | 377 mV             | 340 mV         | 10%     |  |  |  |
| 2.5um-wide 8-signal-wire              | 393 mV             | 302 mV         | 23%     |  |  |  |
| 5.0um-wide 8-signal-wire              | 452 mV             | 259 mV         | 43%     |  |  |  |
| 2000 $\mu m$ -long $Z_{DRV} = 46$ Ohm |                    |                |         |  |  |  |
| 0.8um-wide 8-signal-wire              | 457 mV             | 570 mV         | 25%     |  |  |  |
| 0.8um-wide 16-signal-wire             | 479 mV             | 604 mV         | 26%     |  |  |  |
| 2.5um-wide 8-signal-wire              | 531 mV             | 312 mV         | 41%     |  |  |  |
| 2.5um-wide 16-signal-wire             | 693 mV             | 326 mV         | 53%     |  |  |  |
| 5um-wide 8-signal-wire                | 619 mV             | 246 mV         | 60%     |  |  |  |
| 5um-wide 16-signal-wire               | 741 mV             | 269 mV         | 64%     |  |  |  |
| 4000 $\mu m$ -long $Z_{DRV} = 46$ Ohm |                    |                |         |  |  |  |
| 0.8um-wide 8-signal-wire              | 664 mV             | 798 mV         | 20%     |  |  |  |
| 0.8um-wide 16-signal-wire             | 729 mV             | 891 mV         | 22%     |  |  |  |
| 2.5um-wide 8-signal-wire              | 482 mV             | 615 mV         | 28%     |  |  |  |
| 2.5um-wide 16-signal-wire             | 501 mV             | 677 mV         | 35%     |  |  |  |
| 5um-wide 8-signal-wire                | 607 mV             | 464 mV         | 24%     |  |  |  |
| 5um-wide 16-signal-wire               | 677 mV             | 533 mV         | 21%     |  |  |  |
| 6000 μ <i>m</i> -long                 | $Z_{DRV} = 46$ Ohm |                |         |  |  |  |
| 0.8um-wide 8-signal-wire              | 764 mV             | 871mV          | 14%     |  |  |  |
| 2.5um-wide 8-signal-wire              | 559 mV             | 701 mV         | 25%     |  |  |  |
| 5um-wide 8-signal-wire                | 485 mV             | 567 mV         | 17%     |  |  |  |



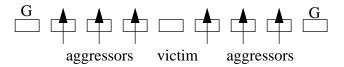
# **Inductance Impacts (cont.)**

|   | Structures   | with inductance    | w/o inductance | % error |
|---|--|--------------------|----------------|---------|
| Interconnect delay                          | 1000 μ <i>m</i> -long  | $Z_{DRV} = 72$ Ohm |                |         |
| comparisons between                         | 0.8um-wide 8-signal-wire                                     | 6.0 ps             | 6.8 ps         | 13%     |
| the cases with and                          | 2.5um-wide 8-signal-wire                                     | 9.0 ps             | 1.8 ps         | 80%     |
| without the<br>consideration of inductance: | 5um-wide 8-signal-wire                                       | 11 ps              | 1.0 ps         | 91%     |
|   | $2000 \mu m  - \log \qquad \qquad Z_{DRV} =  46  \text{Ohm}$ |                    |                |         |
|   | 0.8um-wide 8-signal-wire                                     | 40.6 ps            | 27.2 ps        | 33%     |
|   | 0.8um-wide 16-signal-wire                                    | 43.1 ps            | 27.9 ps        | 35%     |
|   | 2.5um-wide 8-signal-wire                                     | 38.1 ps            | 6.6 ps         | 83%     |
|   | 2.5um-wide 16-signal-wire                                    | 44.2 ps            | 6.7 ps         | 85%     |
|   | 5um-wide 8-signal-wire                                       | 36.8 ps            | 3.3 ps         | 91%     |
|   | 5um-wide 16-signal-wire                                      | 41.3 ps            | 3.4 ps         | 92%     |
|   | 4000 μ <i>m</i> -long  | $Z_{DRV} = 46$ Ohm |                |         |
|   | 0.8um-wide 8-signal-wire                                     | 125 ps             | 105 ps         | 16%     |
|   | 0.8um-wide 16-signal-wire                                    | 127 ps             | 103 ps         | 19%     |
|   | 2.5um-wide 8-signal-wire                                     | 50.0 ps            | 26.7 ps        | 47%     |
|   | 2.5um-wide 16-signal-wire                                    | 67.0 ps            | 26.9 ps        | 60%     |
|   | 5um-wide 8-signal-wire                                       | 48.5 ps            | 13.6 ps        | 72%     |
|   | 5um-wide 16-signal-wire                                      | 61.0 ps            | 13.0 ps        | 79%     |
|   | 6000 μ <i>m</i> -long  | $Z_{DRV} = 46$ Ohm |                |         |
|   | 0.8um-wide 8-signal-wire                                     | 381 ps             | 329 ps         | 14%     |
|   | 2.5um-wide 8-signal-wire                                     | 96 ps              | 73 ps          | 24%     |
|   | 5um-wide 8-signal-wire                                       | 70 ps              | 36 ps          | 49%     |



# **Summary of Inductance Impact Simulations**

- 1. 0.8u-wide or narrower wires do not have significant inductance effects.
- 2. The worst case is all aggressors switch in the same direction



3. In general, with the inductance effects, signal rises faster but delay is longer. The most serious inductance impact is the high-Q ringing, where

$$Q \approx \frac{\sqrt{L/C}}{R_s + R}$$
  $Overshoot = \exp\left(\frac{-\pi}{\sqrt{4Q^2 - 1}}\right)$ 

The rise times shorter than one-half  $2\pi\sqrt{LC}$  incur the worst ringing.

4. The inductive crosstalk noise tops off at lengths of around 4000u to 6000u length.



### **Purpose of Inductance Screen**

Accurate and stable RLC delay and cross-talk estimations still rely on computation-intensive simulations. Determining which nets require the special consideration of inductance is important because designers may apply those RC delay and cross-talk prediction methods, proven to be fast and reliable, to as many nets as possible.



### **Previous Work on Self-Inductance Screen**

 1. A. Deutsch, et al, "When are Transmission-Line Effects Important for On-Chip Interconnects?" IEEE Trans. MTT, Oct. 1997: The error in delay or cross-talk prediction between RC and RLC modelings will exceed 20% if

 $C_L \ll C \ l$  $\frac{R \ l}{2 \ Z_o} \le 1$  $Z_{DRV} < n \ Z_o$ 

However, due to the lack of a ground plane or mesh on chip, the inductive coupling may extend to very long range. Most on-chip wires may not be modeled as uniform RLC transmission lines. Hence,  $Z_o$  is not defined. In general, for about 100ps rise time, those lines shorter than 3000u may not be distributed elements.



### Previous Work on Self-Inductance Screen (cont.)

2. Yehea I. Ismail, et al, "Figures of Merit to Characterize the Importance of On-Chip Inductance," Proc. 35-th DAC, June 1998:

Condition for an interconnect of length l to consider inductance is

$$\frac{t_r}{2\sqrt{LC}} < l < \frac{2}{R}\sqrt{\frac{L}{C}}$$

where  $t_r$  is the signal rise time at the **input** of the driver.

However, the match-or-under-drive assumption used by the approach may not be true for future advanced high speed designs.



### **Self-Inductance Screening Rules**

Based on the simulations performed and the fact that the inductive effects decrease with the increase of length, it was concluded that designers need to consider the inductance of when

$$C_{L} < \frac{1}{8} C l$$

$$l \le \frac{2}{R} \sqrt{\frac{L}{C}}$$

$$2\pi f_{s} Ll > \frac{(Rl + Z_{DRV})}{2}$$
(1)

Under these criteria, the inductive reactance occupies more than one-third of the total reactance, and the delay and cross-talk errors, without considering inductance, exceeded 25%. When the values of Cl and  $C_L$  were close, such as in the 1000um-long structures, the inductance effects (e.g., oscillations) tended to show up. Therefore, under the conditions

$$C_{L} > \frac{1}{8} C l$$

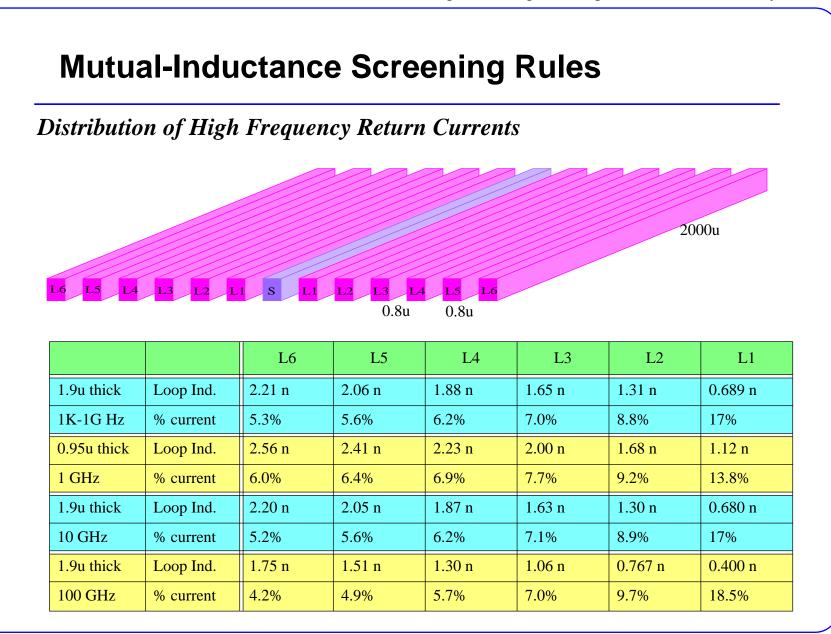
$$l \le \frac{2}{R} \sqrt{\frac{L}{C}}$$

$$2\pi f_{s} Ll > \frac{(Rl + Z_{DRV})}{4}$$

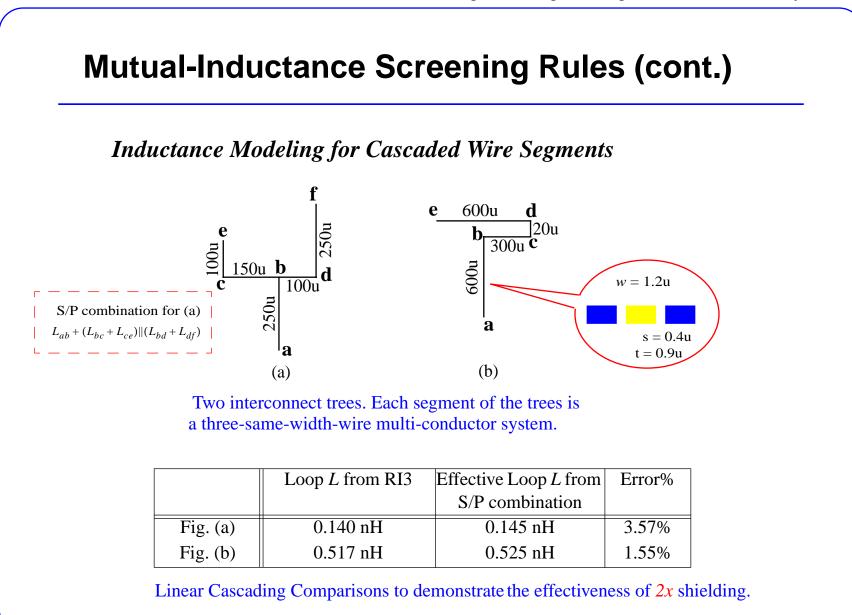
$$(2)$$

the delay and cross-talk errors, without considering inductance, might exceed 25%.

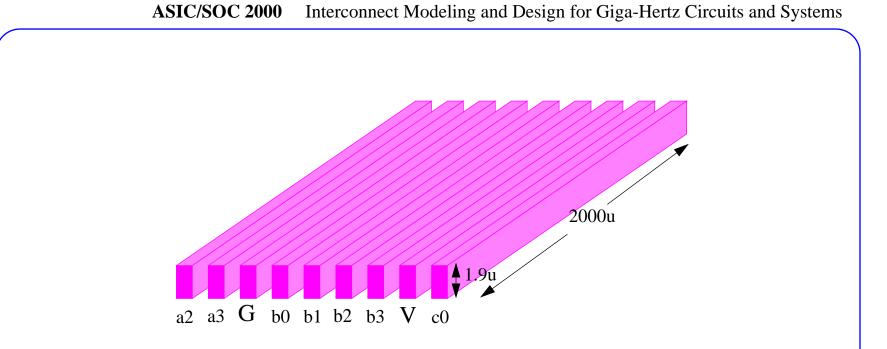












Drivers are Buf130 and receivers are Buf40 (CMOS 0.18u technology).

| signal wires are 2.5u wide with 1.25u spacing | Gnd/Vdd wire<br>width | xtalk noise<br>at <mark>a3</mark> |  |
|---|-----------------------|-----------------------------------|--|
| b0-b3 switch up, c0 switches up               | 7.5u                  | 0.73 mV                           |  |
| b0-b3 switch up, c0 quiet                     | 7.5u                  | 0.66 mV                           |  |
| b0-b3 switch up, e0 switches up               | 10.0u                 | 0.48 mV                           |  |
| b0-b3 switch up; c0 quiet                     | 10.0u                 | 0.41 mV                           |  |

### **Mutual-Inductance Screening Rules (cont.)**

- In order to provide enough current return (shielding), the width of the return path should be at least *two* times the total width of all simultaneously switching signals using that return path.
- Quiet signal wire is as good as a ground wire of equal width for high frequency current return (less than 5% differences on delay and xtalk seen when the vdd wire is replaced by a quiet signal wire in 0.8u case).
- 3. Low frequency currents may always find a ground wire (or ground wires) for return.





### **Efficient Inductance Modelings**

1. The self-partially loop inductance for a trace on top of a ground plane or in-between ground planes depends only on the trace's geometry (length, width, and thickness).

Partially-loop inductance is defined as the loop inductance assuming that currents return only through the ground plane(s).

2. The mutual-partially loop inductance for two traces on top of a ground plane or in-between ground planes depends only on their geometry (lengths, widths, thicknesses, and spacing).



# **Efficient Inductance Modelings (cont.)**

#### **Table-based Inductance Extraction:**

- 1. Run RI3 or FastHenry to determine the self-inductances for traces, microstrip- and strip-lines of several widths, lengths, and thicknesses. Store the results in a table.
- 2. Run RI3 or FastHenry to determine mutual-inductances for two-line traces, microstrip- and strip-lines of several lengths, widths, thicknesses, and spacings. Store the results in a table.
- 3. To determine the inductances of an arbitrary trace, microstripor strip-line, or of an arbitrary two-line traces, microstrip- or striplines, use interpolations, such as cubic spline, from the inductances of the closest line-structures predetermined in previous tables.



# **Inductance Test Chip Benchmark**

#### **Objective:**

- 1. Extract frequency-dependent R, C, and L from test structures
- 2. Compare measurement and simulation

#### **Previous Works:**

- 1. IBM Research Report (1995), A. Deutsch, et. al., IBM
- 2. IITC Poster (1999), R. J. Friar, et. al., U. of Texas at Austin
- 3. IEDM Paper (1999), B. Keveland, et. al., Stanford U.

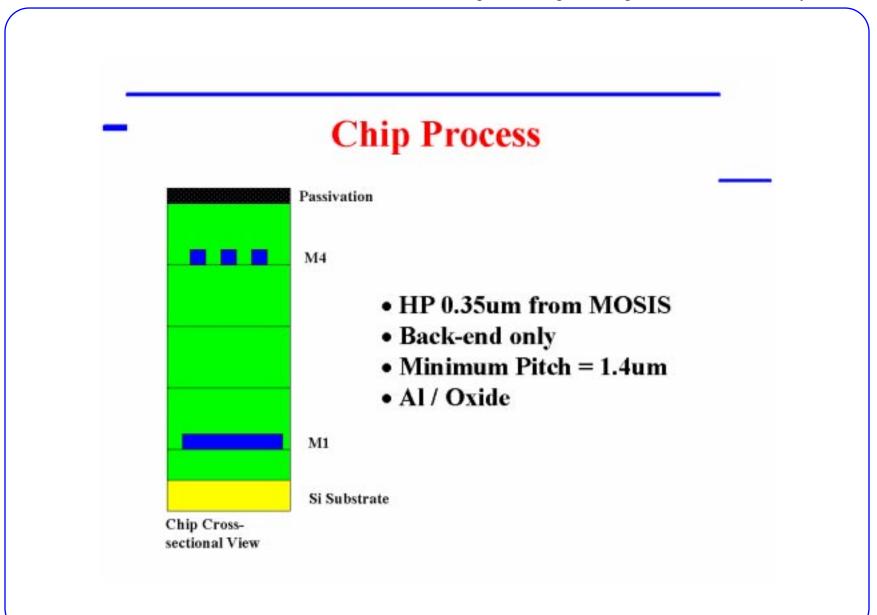




- **6 Types of Test Tracks**
- Microstrip line
- Coplanar waveguide
- Microstrip line under a power rail
- Coplanar split lines
- Horseshoe lines
- Meshes

Chip Size = 4800 um x 6270 um









#### Scattering Parameter

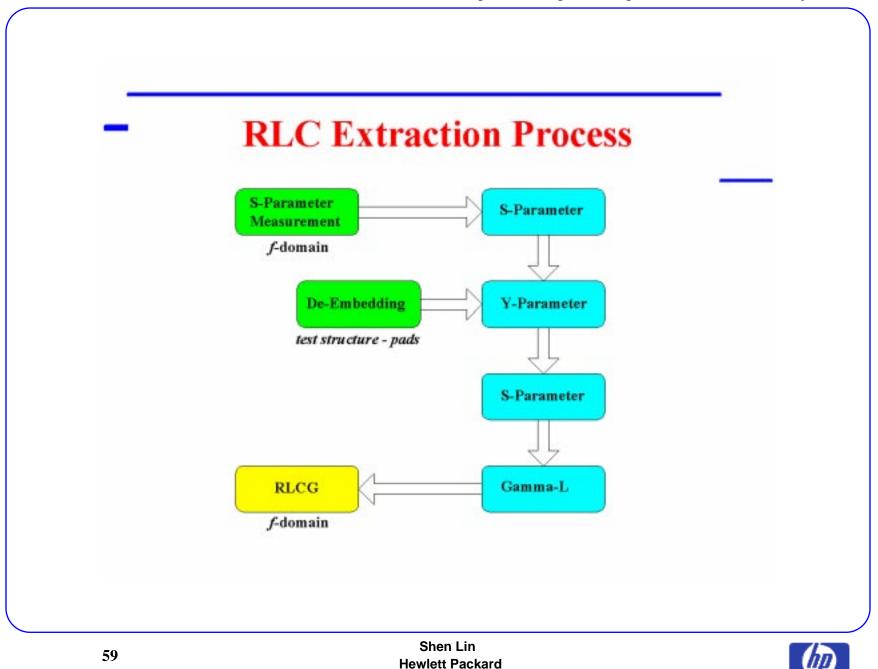
- Relates incident and reflected voltage waves
- 0 < S <1 for a passive system

(good dynamic range for measurement)

#### Measurement System

• HP8510 Network Analyzer (45MHz ~ 20GHz) (upper range limited to ~10GHz by resonance)

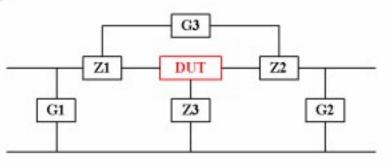




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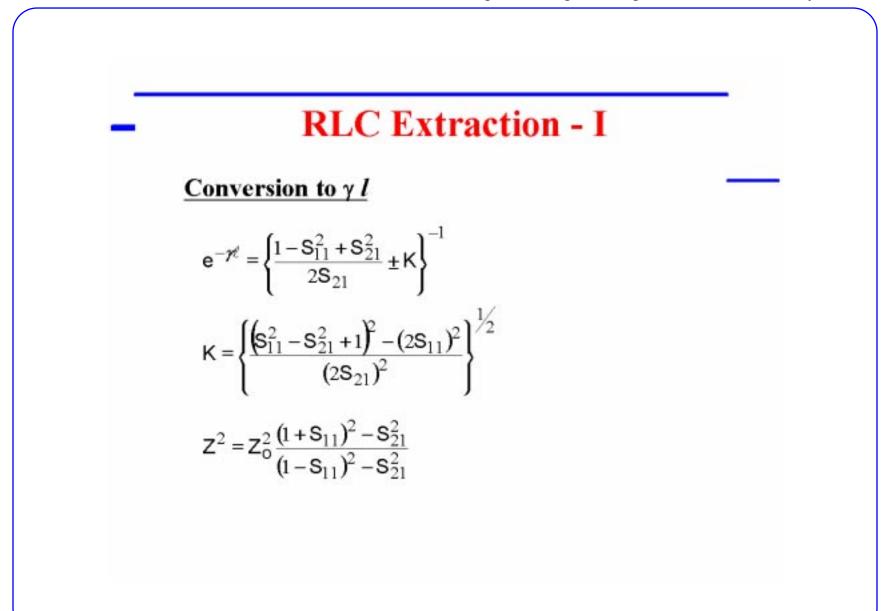


- Subtract shunt admittance from the open measurement. (G1 and G2)
- Subtract series impedance from the through and short measurements. (Z1, Z2, and Z3)
- Subtract coupling capacitance from the open measurement. (G3)

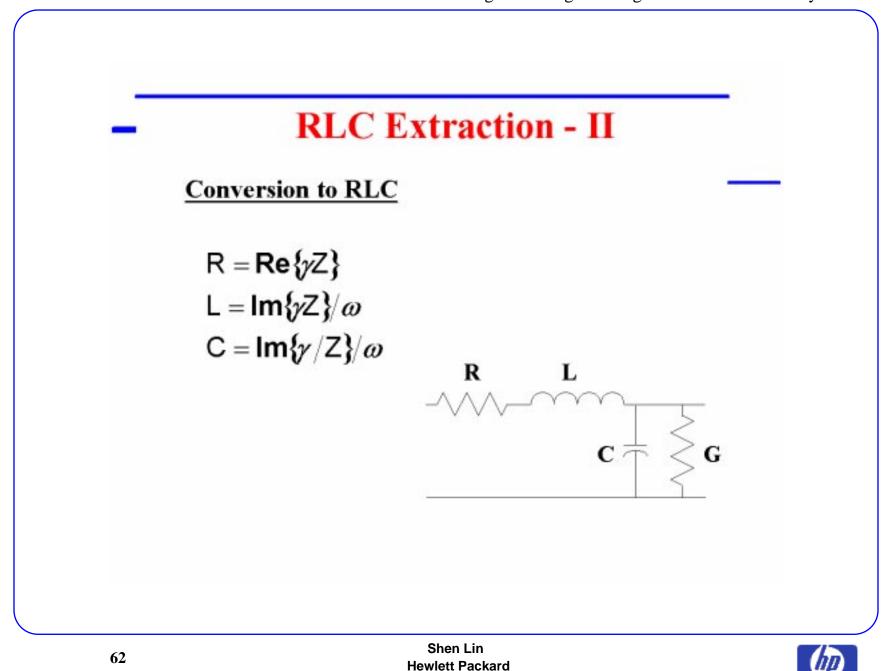


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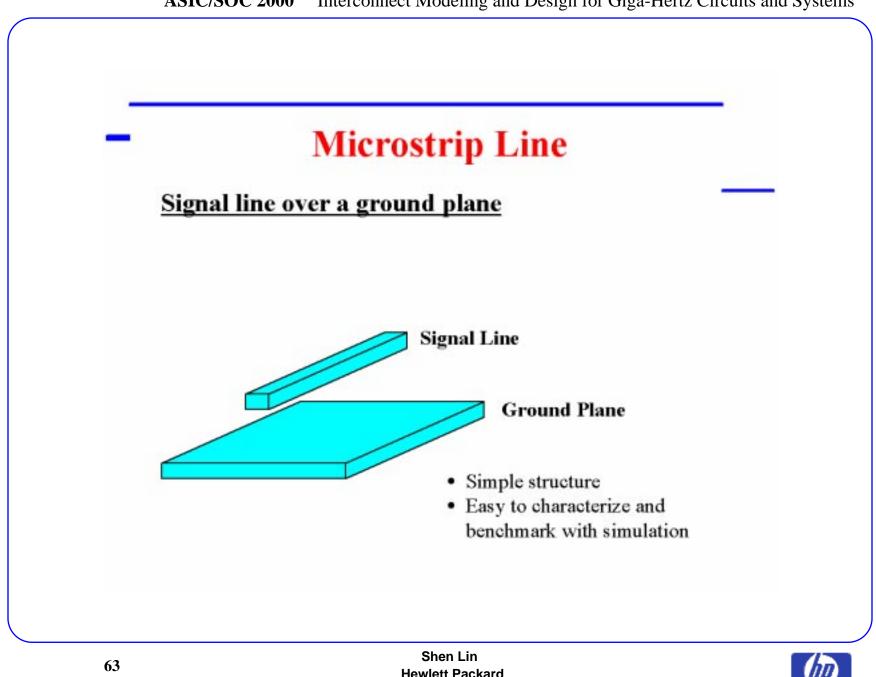




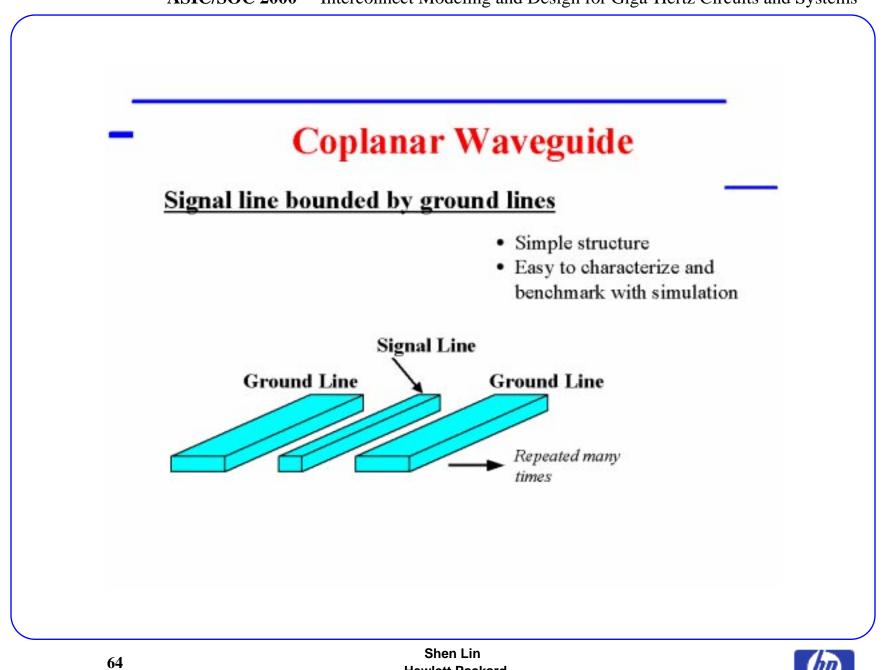


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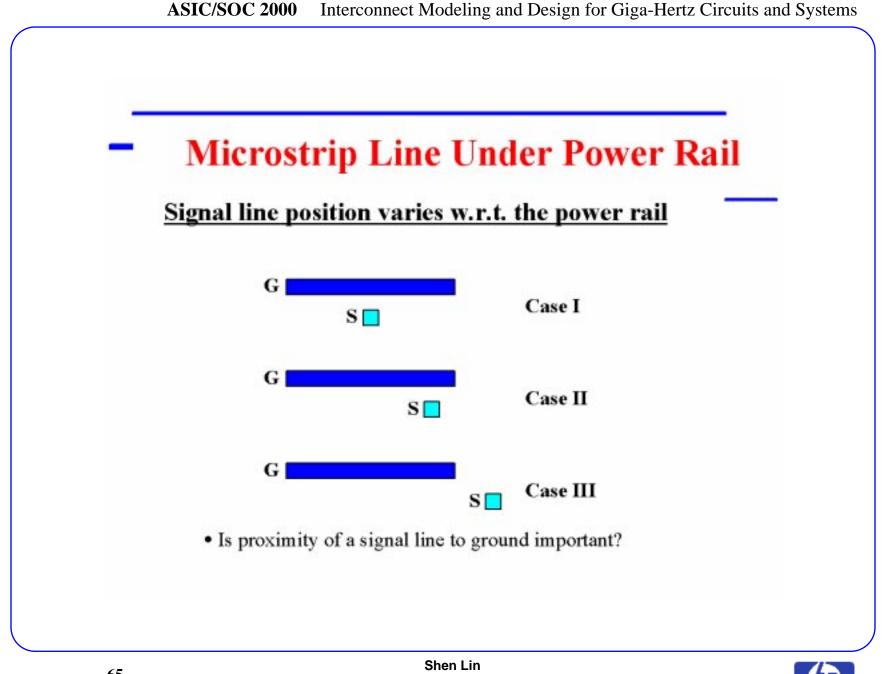
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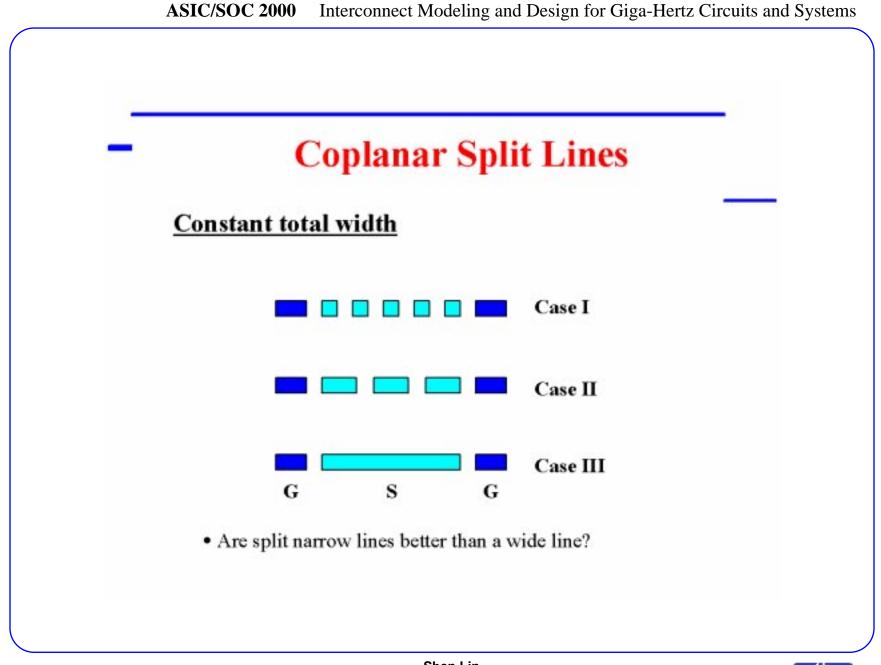
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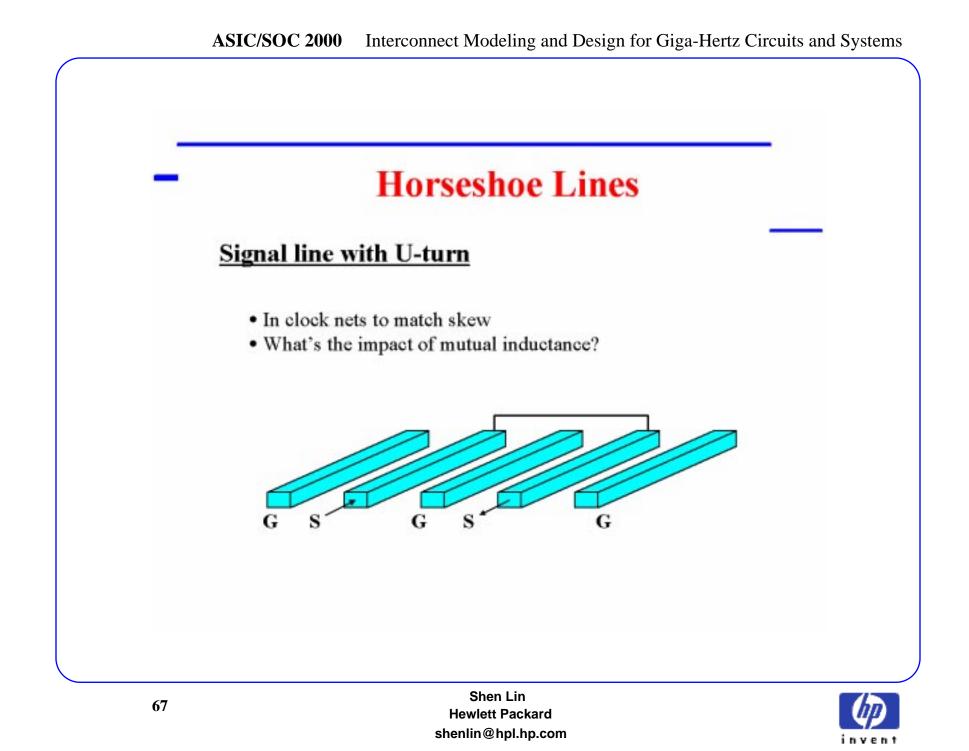


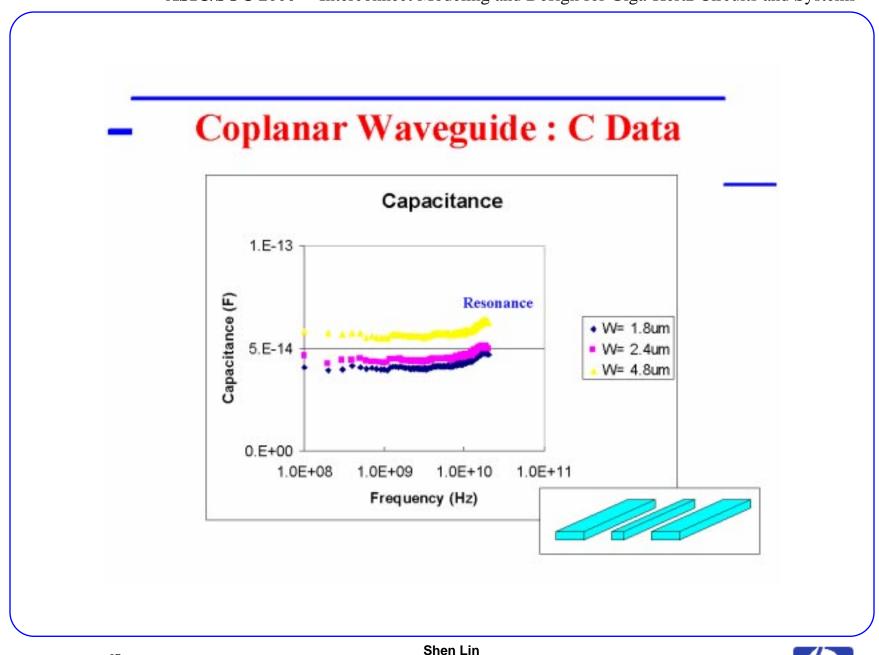


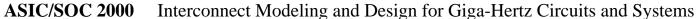
invent



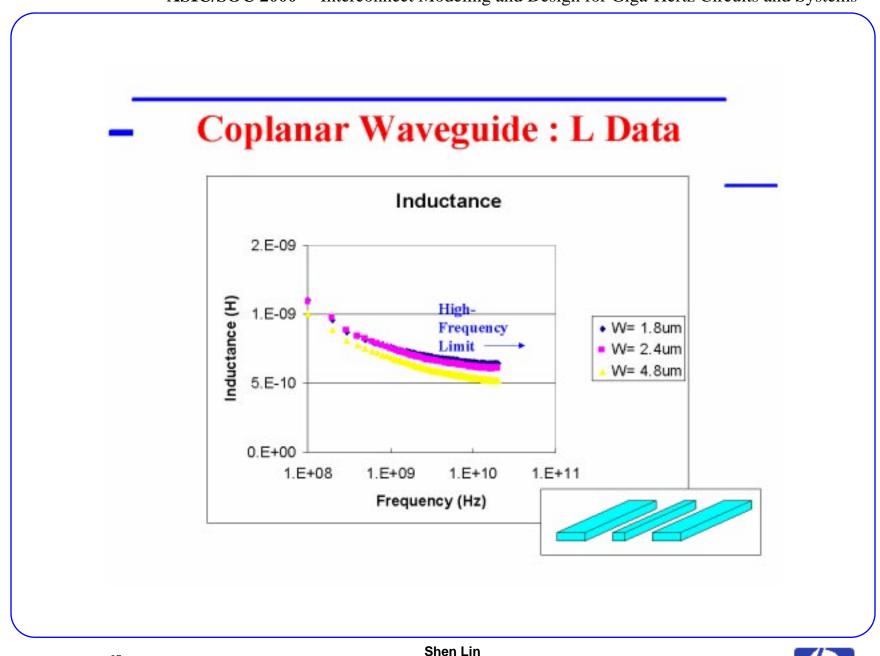


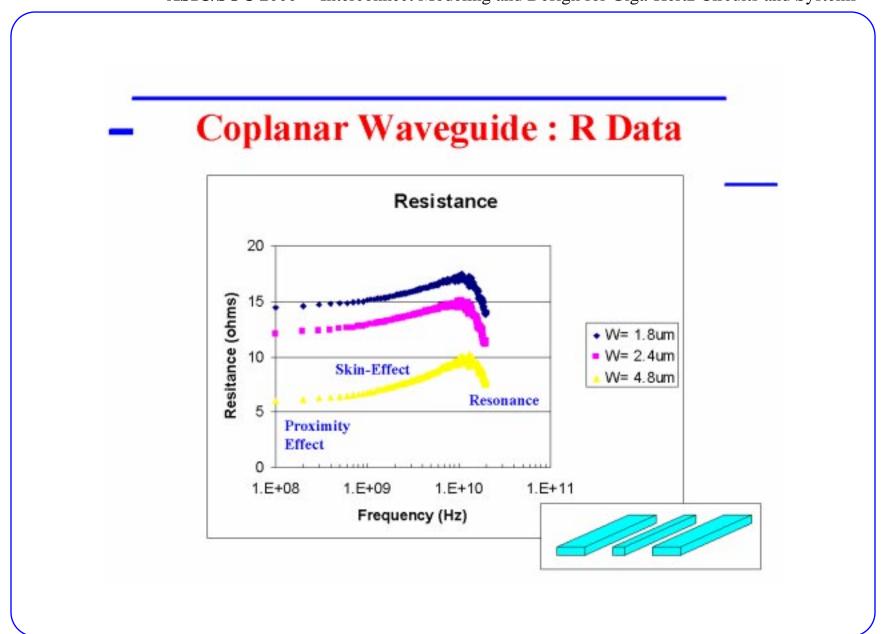


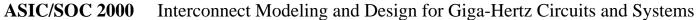




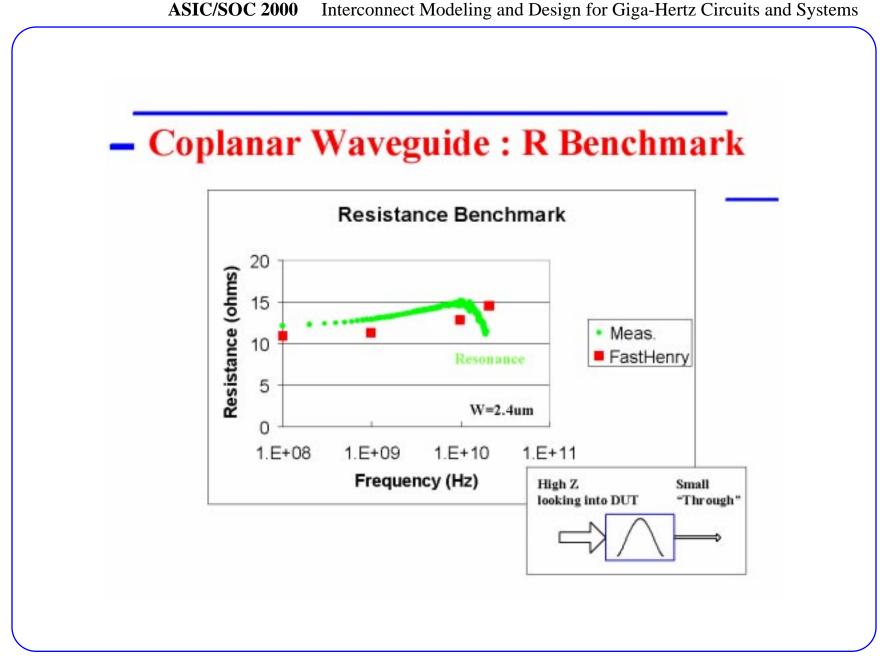




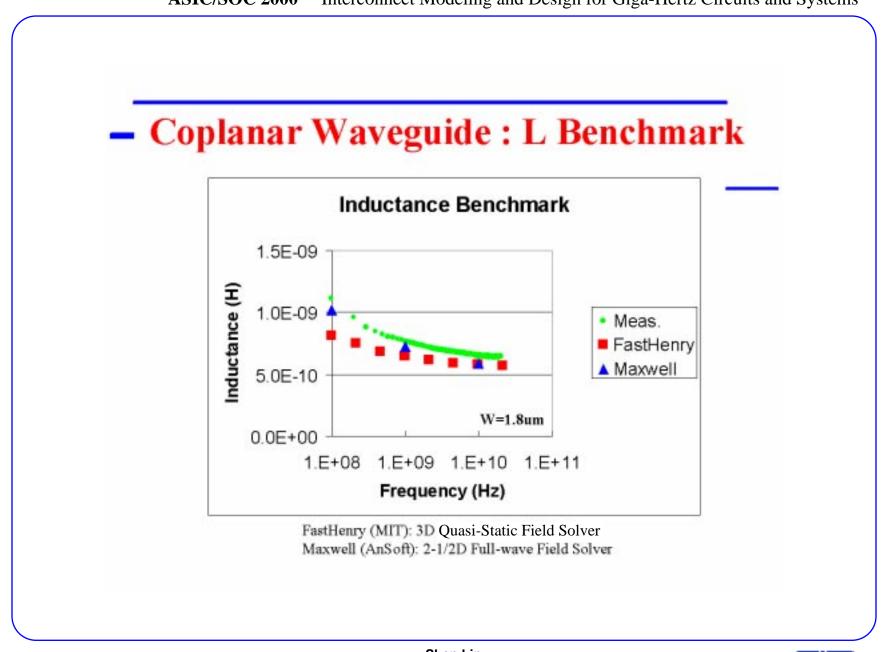




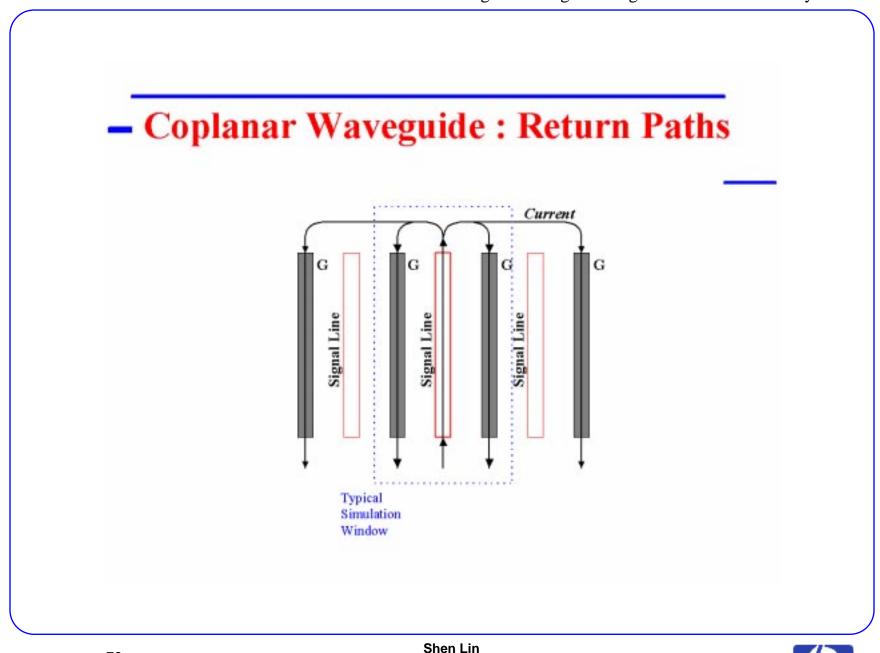






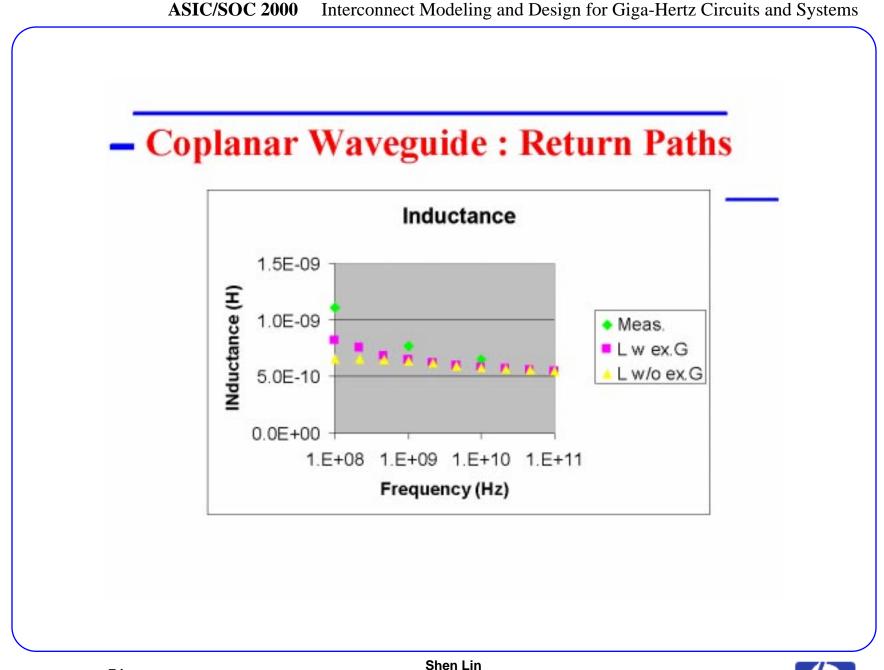


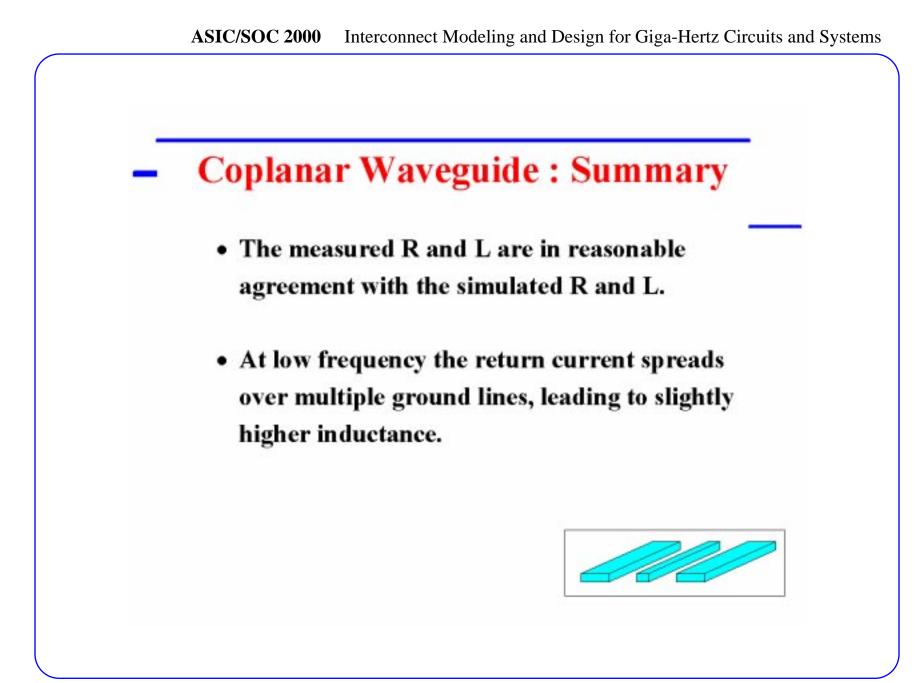




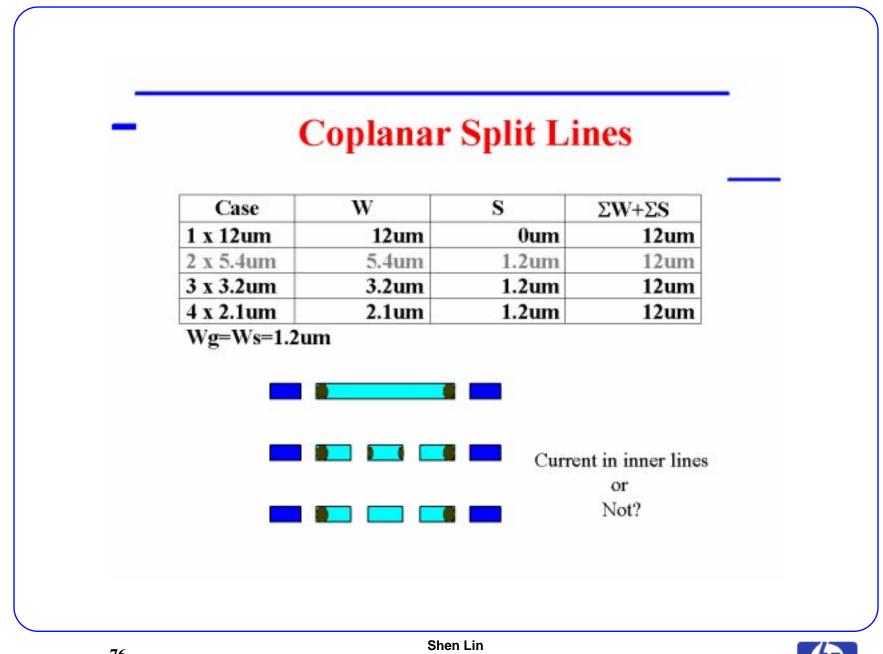
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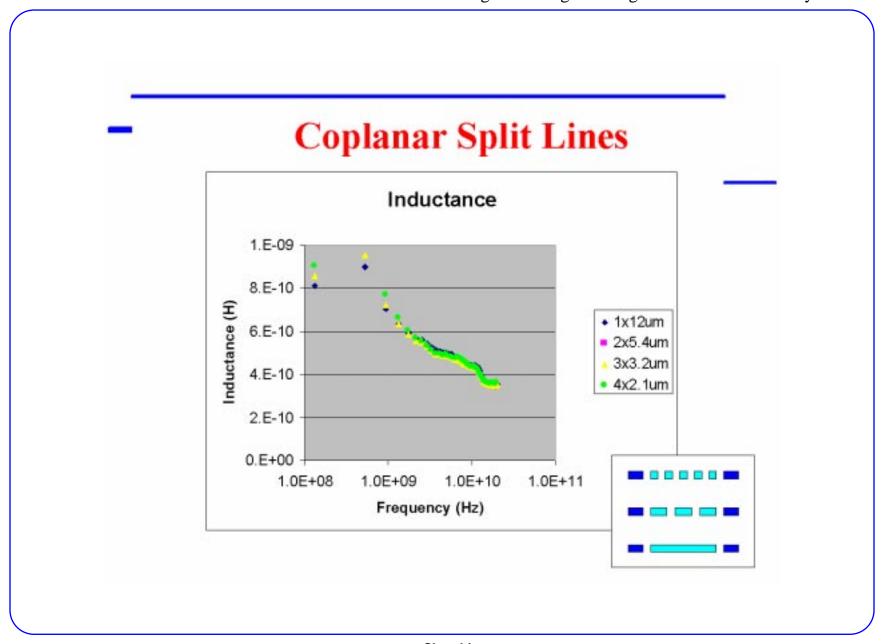




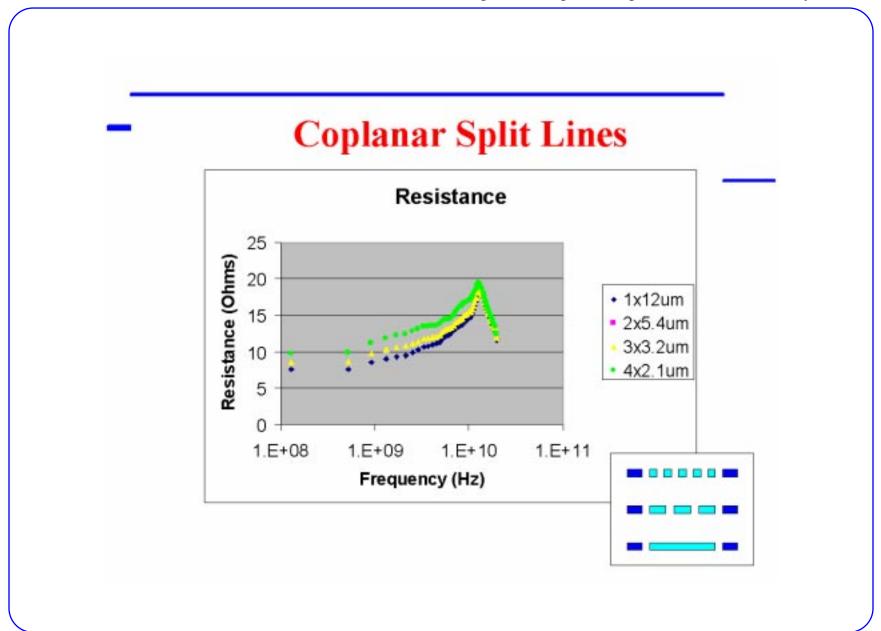




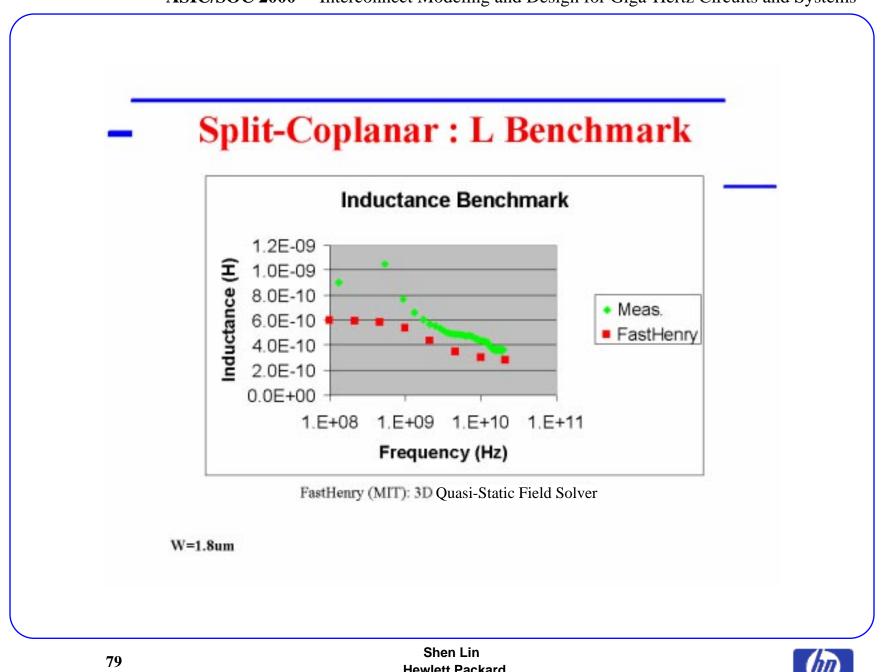
Hewlett Packard shenlin@hpl.hp.com



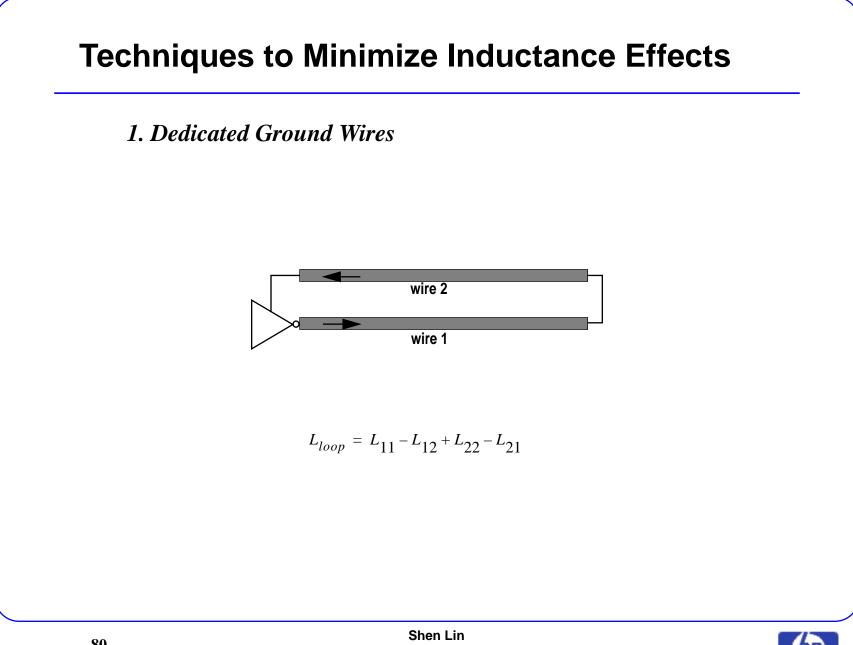


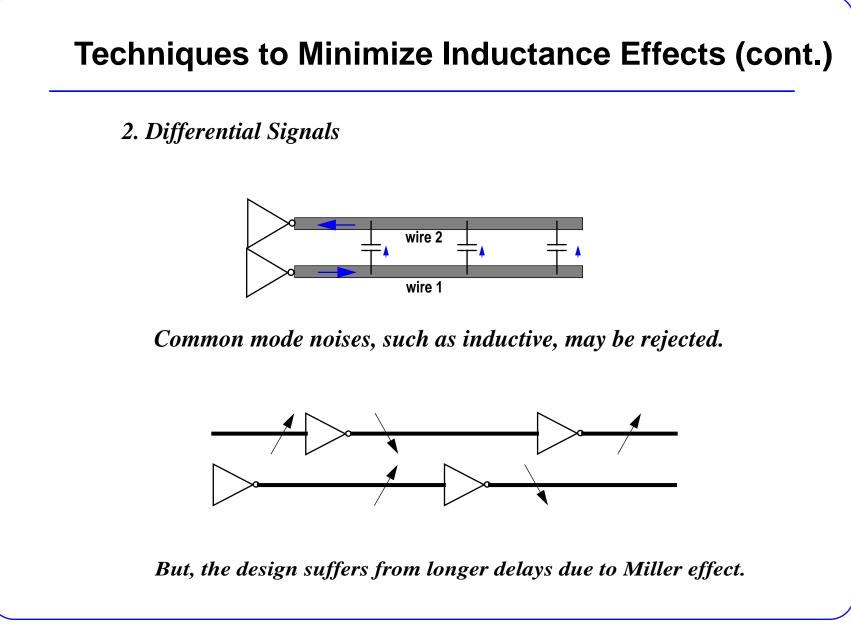




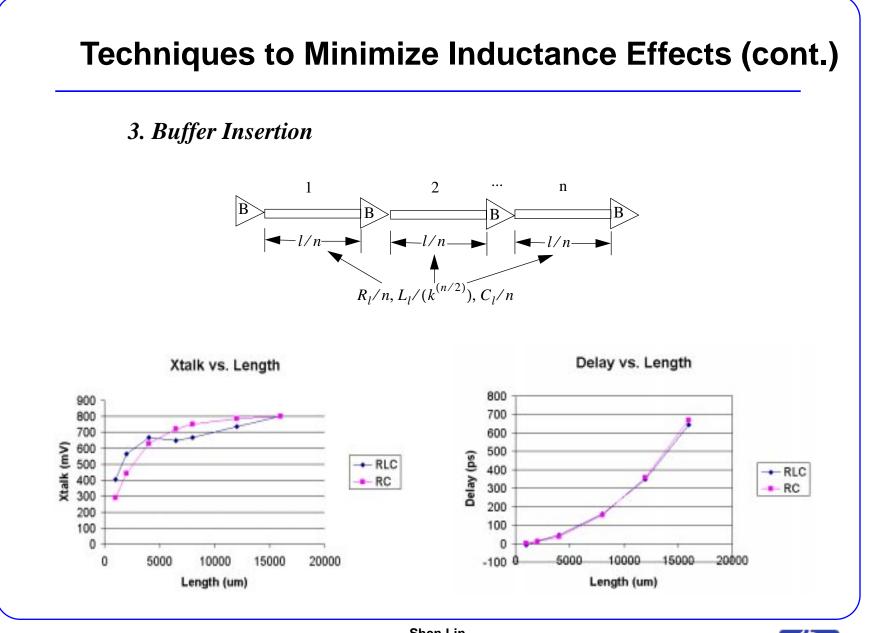


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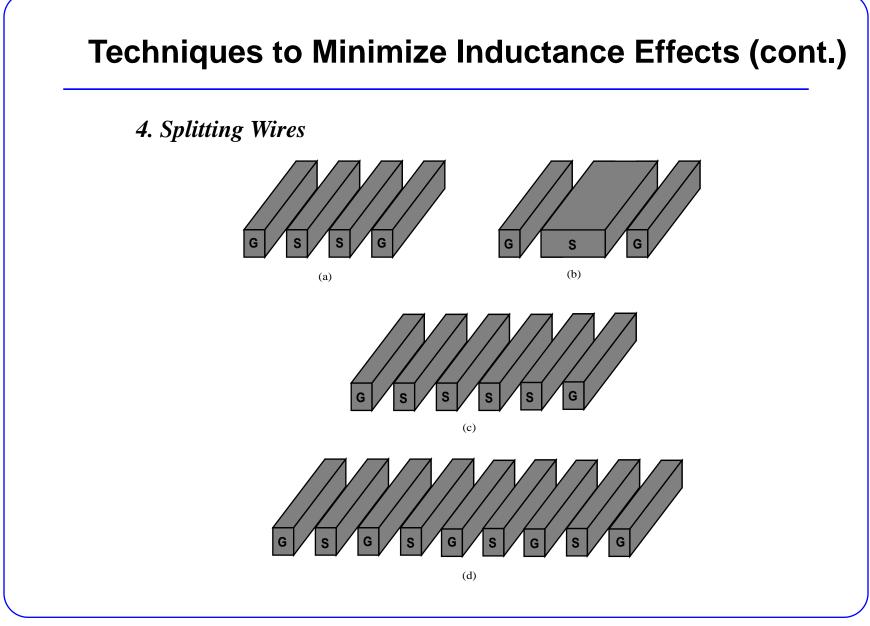




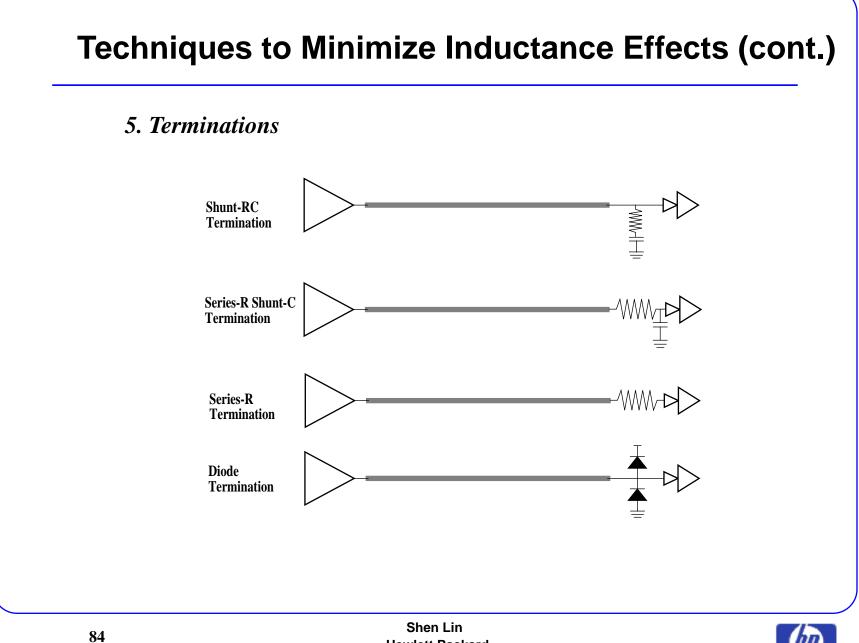












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#### **Shunt-RC Termination**

| R    | С      | Max. Noise | Wire Delay |
|------|--------|------------|------------|
| none | none   | 552 mV     | 21.6 ps    |
| 90   | 0.1 pF | 542 mV     | 28.7 ps    |
| 90   | 0.4 pF | 637 mV     | 34.1 ps    |
| 90   | 0.8 pF | 647 mV     | 37.1 ps    |
| 140  | 0.1 pF | 513 mV     | 28.1 ps    |
| 140  | 0.4 pF | 528 mV     | 30.0 ps    |
| 140  | 0.8 pF | 540 mV     | 31.1 ps    |
| 190  | 0.1 pF | 477 mV     | 27.1 ps    |
| 190  | 0.4 pF | 514 mV     | 27.9 ps    |
| 190  | 0.8 pF | 520 mV     | 28.5 ps    |

#### **Series-R Shunt-C Termination**

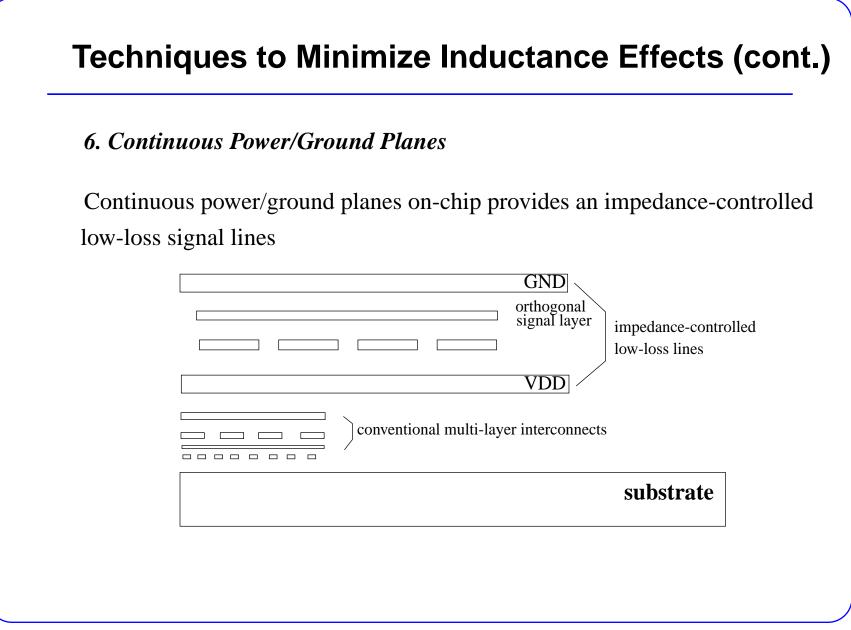
| R    | C      | Max. Noise | Wire Delay |
|------|--------|------------|------------|
| none | none   | 552 mV     | 21.6 ps    |
| 90   | 0.1 pF | 457 mV     | 38.7 ps    |
| 90   | 0.4 pF | 372 mV     | 65.1 ps    |
| 90   | 0.8 pF | 307 mV     | 97.1 ps    |
| 140  | 0.1 pF | 291 mV     | 39.3 ps    |
| 140  | 0.4 pF | 246 mV     | 30.0 ps    |
| 140  | 0.8 pF | 172 mV     | 117 ps     |
| 190  | 0.1 pF | 218 mV     | 45.3 ps    |
| 190  | 0.4 pF | 165 mV     | 85.9 ps    |
| 190  | 0.8 pF | 111 mV     | 140 ps     |



#### **Series-R Termination**

| Z <sub>DRV</sub> | R    | Max. Noise | Wire Delay |
|------------------|------|------------|------------|
| 70               | none | 552 mV     | 21.6 ps    |
| 70               | 40   | 470 mV     | 22.4 ps    |
| 70               | 90   | 397 mV     | 23.6 ps    |
| 70               | 140  | 376 mV     | 24.3 ps    |
| 70               | 190  | 350 mV     | 26.1 ps    |
| 150              | none | 376 mV     | 18.9 ps    |
| 150              | 40   | 339 mV     | 19.6 ps    |
| 150              | 90   | 321 mV     | 20.3 ps    |
| 150              | 140  | 308 mV     | 20.9 ps    |
| 150              | 190  | 295 mV     | 21.5 ps    |







### Summary

We discussed

- 1. the difference between on-chip inductance and off-chip consideration. The on-chip inductance is not scalable and non-orthogonal wires are almost all inductively coupled. Therefore, the on-chip interconnects may not be treated as transmission lines.
- 2. how to calculate inductance. We mention that partial inductance should be preferred and let the circuit simulator determine the return path.
- 3. the skin effect and the proximity effect.
- 4. the inductance impact on delay and cross-talk noise for several interconnect structures, which are mainly caused by over-drive and low resistance. The simulation results lead to the answer of the question "when do we need to consider inductance".
- 5. several important design solutions to cope with inductance effects.
- 6. based on the correct understanding of on-chip inductance, the inductive coupling noise and oscillation caused by over-shoot may be effectively controlled in the future's multi-GHz chips.





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